

Amendments to the Specification:

**Please replace the paragraph beginning on page 2, line 3, with the following
amended paragraph:**

Such corner cube reflectors may, for example, be fabricated via the emerging technology known as MEMS (Micro Electro Mechanical Systems). The term MEMS broadly encompasses many different kinds of devices fabricated on the micron scale, such as sensors, actuators, and instruments. These devices are usually fabricated with integrated circuit technology on a silicon substrate. Such MEMS technology allows the fabrication of microsensors that are very small in size and that are easily transitioned into standard Integrated Circuit (IC) technology facilitates facilities manufacturing.